Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A method of producing an oxide superconducting film comprising:

depositing, on a single-crystal substrate, substances scattered from a raw material due to irradiation with laser beams according to a pulsed-laser deposition method,

performing the irradiation of the raw material is in a manner such that the repetition frequency of the pulse irradiation of the laser beams is divided into at least two steps; a laser frequency of a second step being higher than the laser frequency of a first step and the laser frequency of the second step being less than 100 times the laser frequency of the first step,

wherein a power of the laser beams is greater than or equal to 400 mJ;

a temperature of the single-crystal substrate during the pulsed-laser deposition is more than or equal to 600 °C and less than 1,200 °C;

a gas pressure during the pulsed laser deposition is within the range of 1.33 Pa to 100 Pa; and

an atmospheric gas during the pulsed laser deposition contains oxygen.

2. (Currently Amended) A method of producing an oxide superconducting film according to claim 1, wherein the laser frequency of the second step is not less than 2 times and not more than 40 times as high as the laser frequency of the first step in a case where the laser frequency of the first step is greater than or equal to 1 Hz and less than 20 HZ; and the laser frequency of the second step is not less than 2 times and not more than 5 times as high as the laser frequency of the first step ~~in the case where~~ when the first laser frequency is 20 Hz;

wherein a power of the laser beams is greater than or equal to 400 mJ;

a temperature of the single-crystal substrate during the pulsed-laser deposition is more than or equal to 600 °C and less than 1,200 °C;

a gas pressure during the pulsed laser deposition is within the range of 1.33 Pa to 100 Pa; and

an atmospheric gas during the pulsed laser deposition contains oxygen.

3. – 5. (Cancelled).

6. (Currently Amended) A method of producing an oxide superconducting film according to claim 1, wherein a gas pressure during the pulsed-laser deposition is within the range of 1.33 Pa to [[100]] 66.66 Pa.

7. (Currently Amended) A method of producing an oxide superconducting film according to claim [[6]] 2, wherein a gas pressure during the pulsed-laser deposition is within the range of 1.33 Pa to 66.66 Pa.

8. – 15 (Cancelled).

16. (Previously presented) A method of producing an oxide superconducting film according to claim 1, wherein the oxide superconducting film comprises an RE123 composition, where RE is composed of at least one of a rare-earth element and yttrium.

17. (Currently Amended) A method of producing an oxide superconducting film according to claim [[3]] 2, wherein the oxide superconducting film comprises an RE123 composition, where RE is composed of at least one of a rare-earth element and yttrium.

18. (Currently Amended) A method of producing an oxide superconducting film according to claim [[4]] 6, wherein the oxide superconducting film comprises an RE123 composition, where RE is composed of at least one of a rare-earth element and yttrium.

19. (Currently Amended) A method of producing an oxide superconducting film according to claim [[6]] 7, wherein the oxide superconducting film comprises an RE123 composition, where RE is composed of at least one of a rare-earth element and yttrium.

20. (Cancelled).

21. (New) The method of producing an oxide superconducting film according to claim 1, wherein the power of the laser beam is greater than or equal to 500 mJ.

22. (New) The method of producing an oxide superconducting film according to claim 2, wherein the power of the laser beams is greater than or equal to 500 mJ.